FEB 0 6 7004 EEE CONTRACTOR TO THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 1853

Shoriki NARITA et al.

Docket No. 2001-1876A

Serial No. 10/019,700

Group Art Unit 2825

Filed January 2, 2002

Examiner Igwe U. Anya

BUMP FORMING APPARATUS FOR :
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVAL METHOD
FOR CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVING UNIT FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, AND CHARGE APPEARANCE
SEMICONDUCTOR SUBSTRATE

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

THE CHINEL

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action of October 2, 2004, a two month extension of time being filed concurrently herewith, please amend the above-identified application as follows.